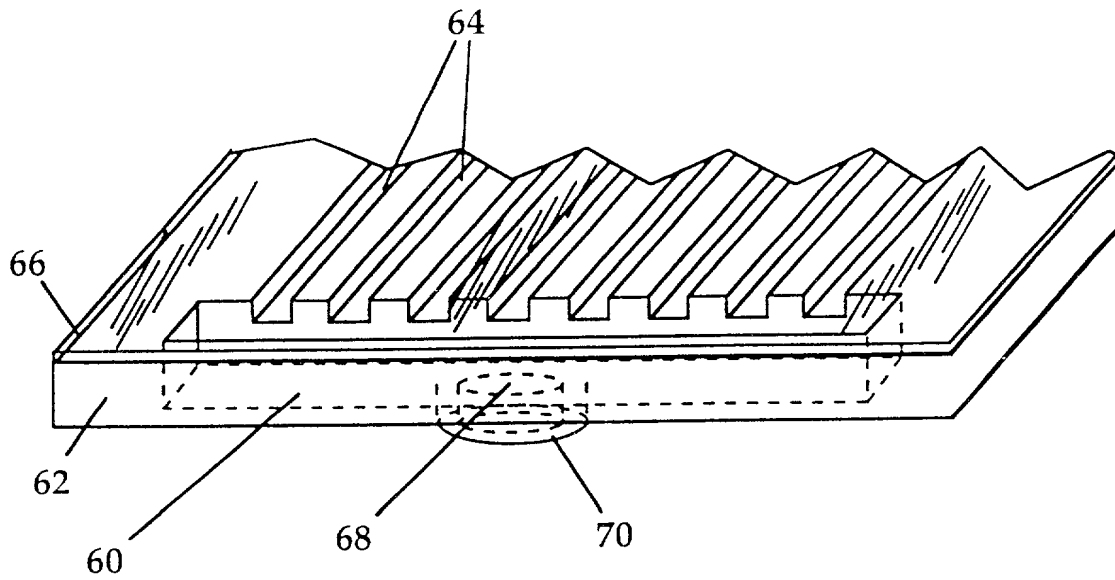
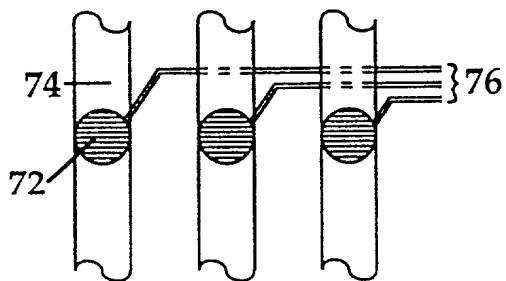


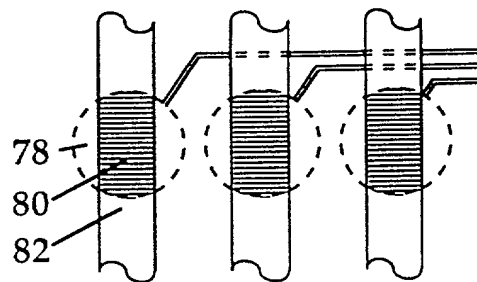
Fig. 1



**Fig. 2**



**Fig. 3A**



**Fig. 3B**

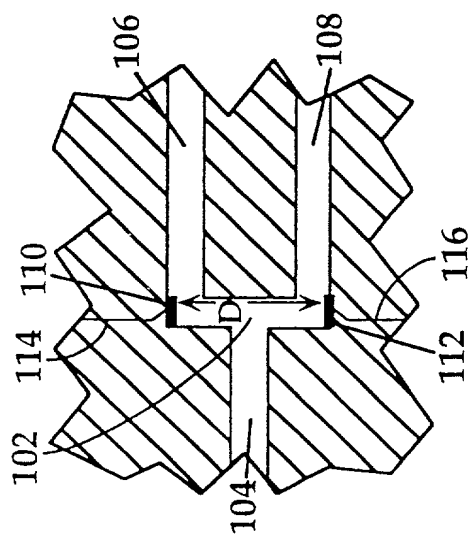


Fig. 4A

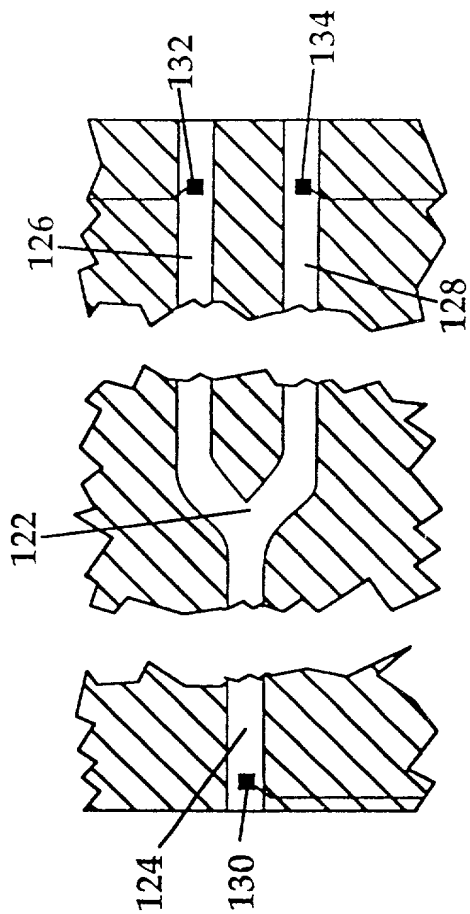


Fig. 4B

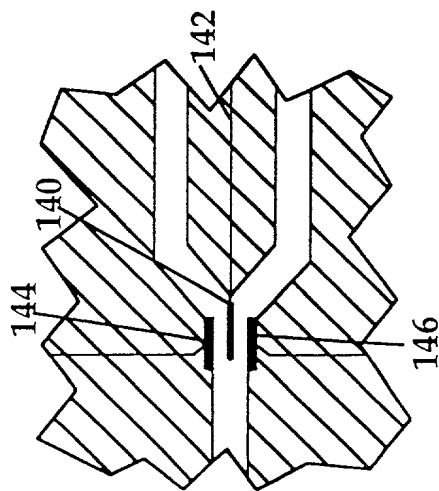


Fig. 4C

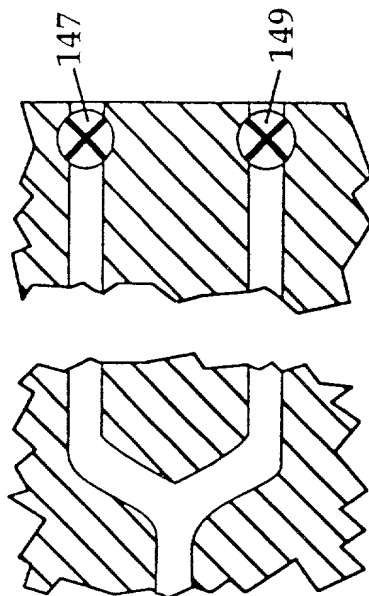
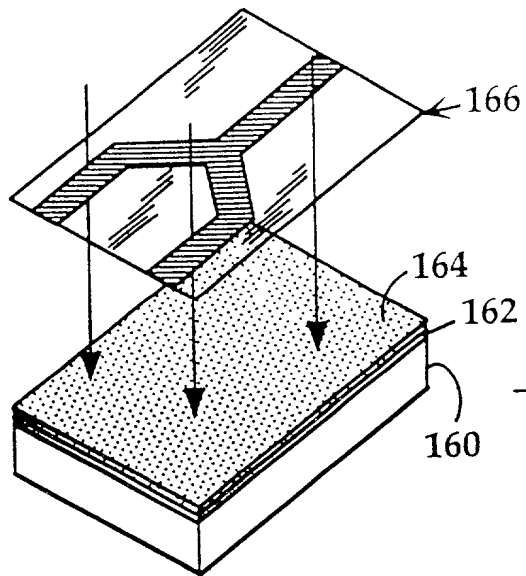
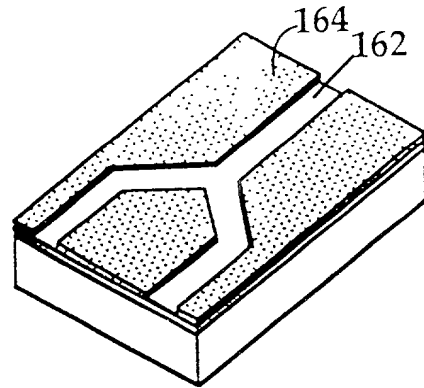


Fig. 4D



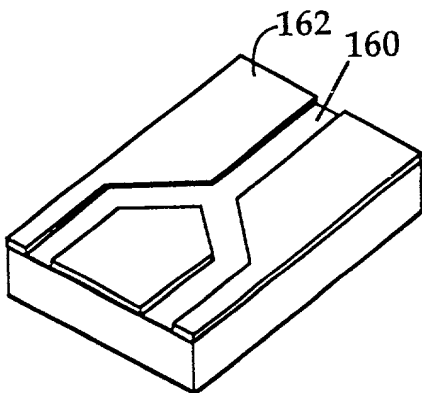
**Fig. 5A**

develop  
→  
and rinse



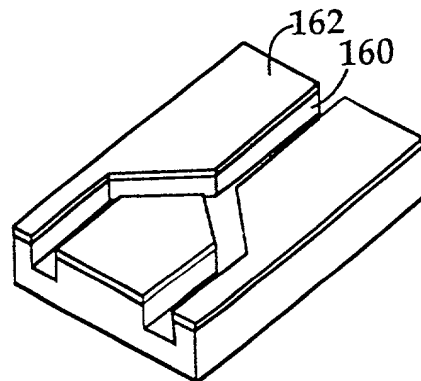
**Fig. 5B**

1. etch  $\text{SiO}_2$
2. remove resist

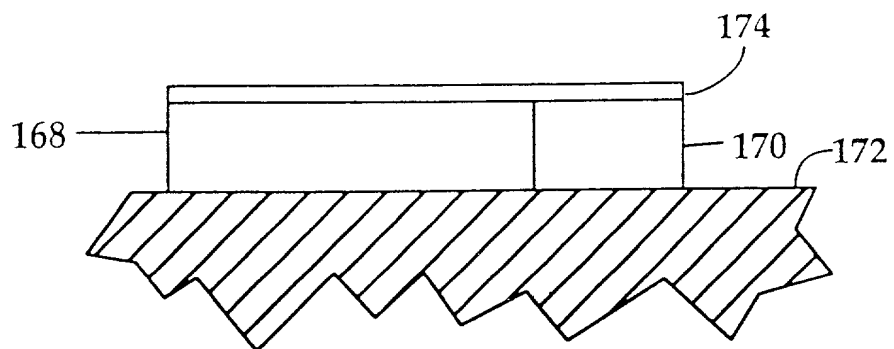


**Fig. 5C**

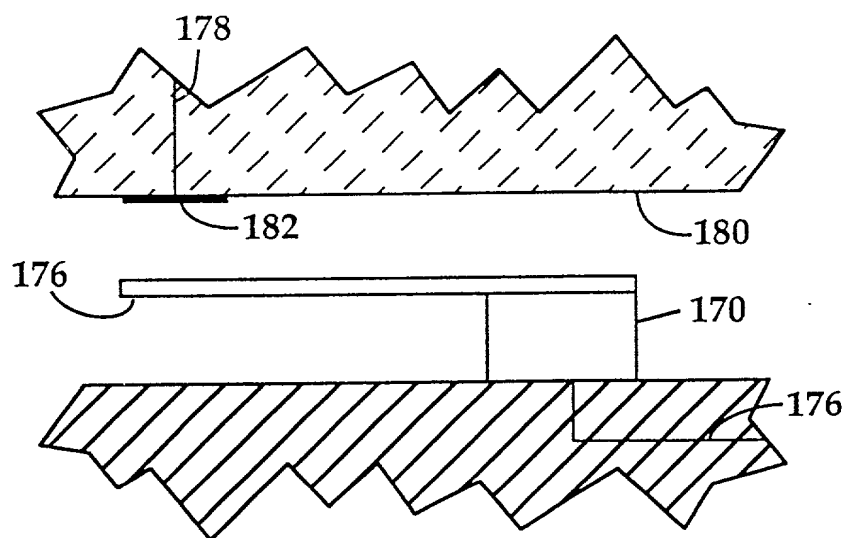
etch Si



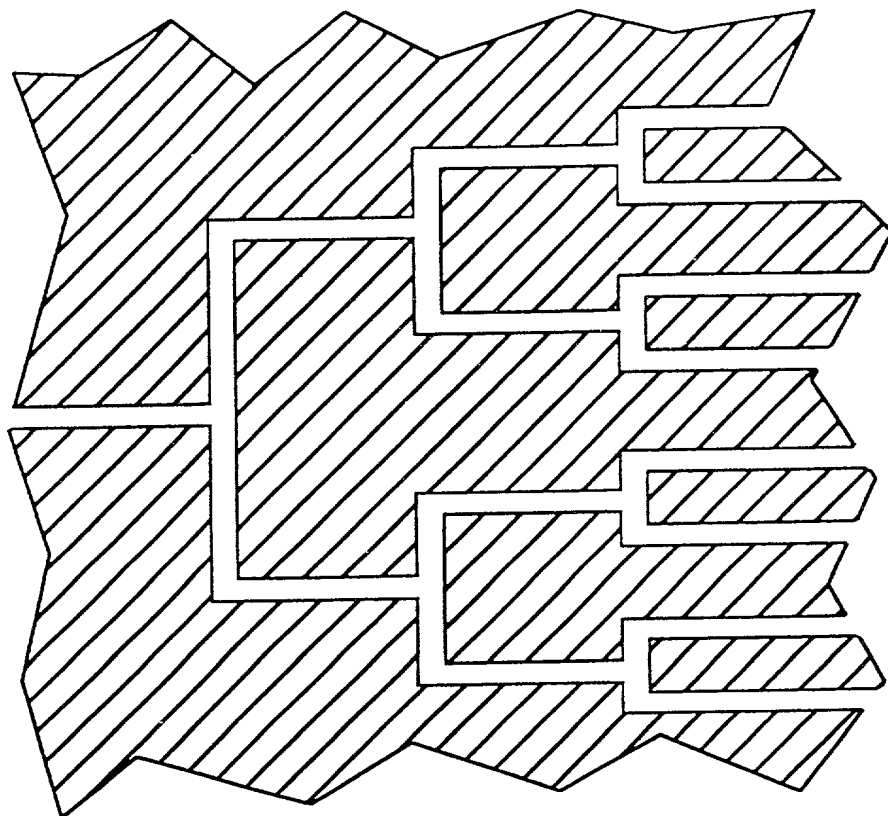
**Fig. 5D**



**Fig. 6A**



**Fig. 6B**



**Fig. 7**